	Application No.	Applicant(s)
Notice of Allowability	, фр.:ош.оп но.	Apprount(s)
	10/742,932	NOGUCHI ET AL.
	Examiner	Art Unit
	Lan Vinh	1765
The MAILING DATE of this communication appear All claims being allowable, PROSECUTION ON THE MERITS IS (herewith (or previously mailed), a Notice of Allowance (PTOL-85) NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RIGOR OF THE OFFICE	OR REMAINS) CLOSED in this ap or other appropriate communication GHTS. This application is subject to	plication. If not included n will be mailed in due course. THIS
1. This communication is responsive to <u>Amendment and respo</u>	onse filed on 2/3/2006.	
2. The allowed claim(s) is/are 2,7-10 and 14-20.		
3. Acknowledgment is made of a claim for foreign priority und	der 35 U.S.C. § 119(a)-(d) or (f).	
a) ⊠ All b) ☐ Some* c) ☐ None of the:		
1. Certified copies of the priority documents have been received.		
2. Certified copies of the priority documents have been received in Application No		
3. Copies of the certified copies of the priority documents have been received in this national stage application from the		
International Bureau (PCT Rule 17.2(a)).		
* Certified copies not received:		
Applicant has THREE MONTHS FROM THE "MAILING DATE" of noted below. Failure to timely comply will result in ABANDONMITHIS THREE-MONTH PERIOD IS NOT EXTENDABLE.		complying with the requirements
4. A SUBSTITUTE OATH OR DECLARATION must be submit INFORMAL PATENT APPLICATION (PTO-152) which gives	ted. Note the attached EXAMINER s reason(s) why the oath or declara	'S AMENDMENT or NOTICE OF ation is deficient.
5. CORRECTED DRAWINGS (as "replacement sheets") must be submitted.		
(a) ☐ including changes required by the Notice of Draftsperso	on's Patent Drawing Review (PTO-	·948) attached
1) hereto or 2) to Paper No./Mail Date		·
(b) including changes required by the attached Examiner's Paper No./Mail Date	Amendment / Comment or in the C	Office action of
Identifying indicia such as the application number (see 37 CFR 1.6 each sheet. Replacement sheet(s) should be labeled as such in the	34(c)) should be written on the drawi e header according to 37 CFR 1.121(ngs in the front (not the back) of d).
6. DEPOSIT OF and/or INFORMATION about the depos attached Examiner's comment regarding REQUIREMENT F	it of BIOLOGICAL MATERIAL I OR THE DEPOSIT OF BIOLOGIC	must be submitted. Note the AL MATERIAL.
-		
Attachment(s)		
1. ☐ Notice of References Cited (PTO-892)	5. Notice of Informal F	Patent Application (PTO-152)
2. Notice of Draftperson's Patent Drawing Review (PTO-948)	6. Interview Summary	(PTO-413),
3. Information Disclosure Statements (PTO-1449 or PTO/SB/08	Paper No./Mail Da s), 7. ⊠ Examiner's Amendr	te nent/Comment
Paper No./Mail Date4. ☐ Examiner's Comment Regarding Requirement for Deposit	8. 🛛 Examiner's Stateme	ent of Reasons for Allowance
of Biological Material	9.	
		Lan Vinh AU 1765
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EXAMINER'S AMENDMENT

1. An examiner's amendment to the record appears below. Should the changes and/or additions be unacceptable to applicant, an amendment may be filed as provided by 37 CFR 1.312. To ensure consideration of such an amendment, it MUST be submitted no later than the payment of the issue fee.

The application has been amended as follows:

On page 2 of the Preliminary Amendment filed on 12/23/2003, "now US Patent 6.723,631" has been inserted after "September 28, 2001,"

Allowable Subject Matter

2. Claims 2, 7-10, 14-18 allowed.

The following is an examiner's statement of reasons for allowance:

Regarding claim 2, the applicants have presented a persuasive argument, see pages 10-11 of the response filed on 2/3/2006, that the cited prior art of record, taken alone or in combination, fails to disclose or suggest a fabrication method of a semiconductor circuit device comprises a step of carrying out hydrogen.anneal treatment to he upper surface of said first insulation film and the upper surface of said metal interconnect after a cleaning step, in combination with the rest of the steps/limitations of claim 2. The closest cited prior art of Mikagi (US 6,274,923) discloses a method of fabricating a semiconductor device comprises a step of carrying out a plasma treatment (NH3) to the upper surface of the protective film 110 formed

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above the upper surface of the first insulation film 104 and the upper surface of said metal interconnect 107 after a polishing step (fig. 3C)

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Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Conclusion

3. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Lan Vinh whose telephone number is 571 272 1471. The examiner can normally be reached on M-F 8:30-5:30 PM.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Nadine Norton can be reached on 571 272 1465. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov.

February 28, 2006